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(54) **COMPOSITE SUBSTRATE AND METHOD
FOR PRODUCING COMPOSITE SUBSTRATE**

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ABSTRACT

A composite substrate includes: a support substrate; a piezo-electric film arranged above the support substrate; and a joining layer arranged between the support substrate and the piezoelectric film, wherein the piezoelectric film includes a polycrystalline substance having a degree of c-axis orientation determined by a Lotgering method of 80% or less, and wherein the joining layer includes an amorphous substance.

